

JUL 28 2005

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application Serial No. 10/671,922
Confirmation No. 8459
Filing Date September 24, 2003
Inventor Garo J. Derderian
Assignee Micron Technology, Inc.
Group Art Unit 2812
Examiner Lynne Ann Gurley
Attorney's Docket No. MI22-2296
Customer No. 021567
Title: Atomic Layer Deposition Methods, and Methods of Forming Materials Over
Semiconductor Substrates

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

CERTIFICATE OF FACSIMILE TRANSMISSION UNDER 37 CFR § 1.8

I hereby certify that the following papers are being facsimile transmitted to the
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2. Response to May 20, 2005 Office Action

Dated: July 28, 2005By: 

Jennifer Gaines, Legal Assistant
Telephone No. (509) 624-4276
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FEE DEFICIENCY

Although it is believed that no fees are due, the Commissioner is hereby
authorized to charge any fees under 37 C.F.R. 1.16 and 1.17 which may be required by
this paper to Deposit Account No. 23-0925.

Dated: July 28, 2005By: 

David G. Latwesen, Ph.D.
Reg. No. 38,533

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RESPONSE TO MAY 20, 2005 OFFICE ACTION

To: Commissioner for Patents
P.O. Box 1450
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AMENDMENTS

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